

TESTING DEVICE, AND TESTING METHOD FOR SEMICONDUCTOR CLEANING APPARATUS

ABSTRACT

5

The present disclosure provides a testing device, and a testing method for a semiconductor cleaning apparatus, and relates to the field of semiconductor technology. Wafer jumping can be detected based on the testing device, adoption of manual visual inspection can be avoided, detection accuracy of wafer jumping can be improved, a wafer can be prevented from being scratched and broken, and an etching effect can also be improved. The testing device includes: a testing balance mechanism, an elastic assembly, and a testing assembly, and two ends of the elastic assembly are connected to the testing balance mechanism and the testing assembly, respectively; one end of the testing balance mechanism is connected to the elastic assembly, and the other end of the testing balance mechanism is configured to support a wafer to be cleaned in a process tank; the testing balance mechanism is configured to change, in a case where the wafer to be cleaned jumps, a deformation amount of the elastic assembly based on the lever principle; and the testing assembly is configured to measure the deformation amount of the elastic assembly.

20

FIG. 1